

ASMJP.145AUS

PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant	:	Chou San Nelson Loke, et al.
Appl. No.	:	10/781,247
Filed	:	February 18, 2004
For	:	SYSTEM AND METHOD OF CVD CHAMBER CLEANING
Examiner	:	Keath Chen
Group Art Unit	:	1709

**AMENDMENT AND RESPONSE TO FINAL OFFICE ACTION**

**Mail Stop: AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action electronically sent on December 26, 2008, please reconsider the present application in light of the following amendments and comments.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 4 of this paper.